

Advances in mirror technology for X-ray, EUV lithography, laser and other applications - 7-8 August 2003, San Diego, California, USA

SPIE - Advances In Mirror Technology For X Ray Euv Lithography Laser And Other Applications Proceedings Of Spie PDF Book

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v. 5193.
Proceedings of SPIE--the International Society for Optical Engineering ;

v. 5193
SPIE proceedings series,Advances in mirror technology for X-ray, EUV lithography, laser and other applications - 7-8 August 2003, San Diego, California, USA

Notes: Includes bibliographical references and index.
This edition was published in 2004

Tags: #David #L #Shealy

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ID 90055 Online 28 January 2008.
Keywords : geometrical optics; caustic theory; aberration theory; optical design;



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optimization; genetic algorithms; differential equations; laser beam shaping; numerical analysis; and mathematical physics. Since the nanoprofiler does not use a reference surface, it should be capable of measuring free-form surfaces with a high degree of accuracy.

Microlithography: Science and Technology

Krzywinski: Fluence scan: an unexplored property of a laser beam, Opt.

Front Matter: Volume 8848, Proceedings of SPIE

Varying the photon energy around the Si- absorption edge enabled us to distinguish between surface defects and in-depth defects that cannot be seen at the multilayer surface. Luqman Akasyah Bin Zaini PhD Ongoing 2017 onwards Sole Supervisor Commercial carbon cloth based hybrid nanomaterials for photocatalysis 16.

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SPIE 7636 , 76361J-1 2010. The sonic surface is shown as a solid contour line; the dashed contour marks the position of the critical surface. The 2% in-band region around 13.

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